

Ultrasensitive measurement of MEMS cantilever displacement sensitivity below the shot noise limit

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The displacement of micro-electro-mechanical-systems (MEMS) cantilevers is used to measure a variety of phenomena in devices ranging from force microscopes for single spin detection[1] to biochemical sensors[2] to uncooled thermal imaging systems[3]. The displacement readout is often performed optically with segmented detectors or interference measurements. Until recently, various noise sources have limited the minimum detectable displacement in MEMS systems, but it is now possible to minimize all other sources[4] so that the noise level of the coherent light field, called the shot noise limit (SNL), becomes the dominant source. Light sources displaying quantum-enhanced statistics below this limit are available[5, 6], with applications in gravitational wave astronomy[7] and bioimaging[8], but direct displacement measurements of MEMS cantilevers below the SNL have been impossible until now. Here, we demonstrate the first direct measurement of a MEMS cantilever displacement with sub-SNL sensitivity, thus enabling ultratrace sensing, imaging, and microscopy applications. By combining multi-spatial-mode quantum light sources with a simple differential measurement, we show that sub-SNL MEMS displacement sensitivity is highly accessible compared to previous efforts that measured the displacement of macroscopic mirrors with very distinct spatial structures crafted with multiple optical parametric amplifiers and locking loops[9]. We apply this technique to a commercially available microcantilever in order to detect displacements 60% below the SNL at frequencies where the microcantilever is shot-noise-limited. These results support a new class of quantum MEMS sensor whose ultimate signal to noise ratio is determined by the correlations possible in quantum optics systems.

Optical beam displacement is a widely used signal transduction technique found in a variety of micro and nano-mechanical sensors. The precision afforded by the optical readout of MEMS displacements results in high signal to noise ratios (SNR), ultrasensitive beam displacements, and in turn, inference of physical phenomena on the order of $\text{fm}/\sqrt{\text{Hz}}$ [4, 10, 11]. While MEMS cantilever applications such as atomic force microscopes or explosives detectors have routinely made use of optical readout, these applications are plagued by disparate noise sources. The combined noise in a MEMS displacement measurement serves to limit the sensitivity, so that a change in the frequency or amplitude of displacement brought on - for example - by the interaction with a sin-

gle analyte molecule, is impossible to discern if it falls within the noise statistics. One important noise source is the cantilever's own thermal motion, which decays inversely with oscillation frequency[4]. In practical applications, displacement measurements performed with large spring constant microcantilevers at high frequencies not only reduce the thermal noise relative to other noise sources, but also enable high speed imaging and sensing applications[12].

Two other important noise sources are the photon shot noise and back action noise, which results from perturbations in the microcantilever position due to photon momentum-noise transfer. The shot noise limit is often referred to interchangeably as the standard quantum limit (SQL), but - in keeping with the MEMS literature - we define the SQL to be the limit at which back action noise has observable effects on displacement sensitivity[13]. A growing number of efforts have been made to achieve sensitivity below the SQL via back action evading techniques[13–16], but the SNL provides a more fundamental limit to sensitivity which cannot be improved upon with optical readout using classical light. The variances due to back action noise and shot noise respectively are given by (see also online material)

$$\langle(\Delta x)^2\rangle_{back} = \frac{8Ph\Delta fQ^2}{c\lambda k^2}; \quad \langle(\Delta x)^2\rangle_{SNL} = \frac{hc\lambda\Delta f}{8\pi^2P} \quad (1)$$

where x is the displacement, P is the optical power, Δf is the signal bandwidth, Q the microcantilever mechanical quality factor, k is the spring constant, h is Planck's constant, c the speed of light, and λ the optical wavelength. An obvious approach to reducing the shot noise floor relative to the signal is to increase the optical power, which leads to higher SNR, but as Eq. 1 shows, doing so places limits on the sensitivity via increased back action noise. This leads to a conundrum in which the sensitivity cannot be arbitrarily improved by increasing the optical power above mW levels unless back action evading techniques are utilized to reduce the SQL[13–16] to the shot noise limit. However, higher optical powers can damage photosensitive ligands and introduce excess laser noise that greatly exceeds both the SNL and the SQL[4], limiting the viability of this approach.

On the other hand, sensitivity below the SNL is only possible with states of light exhibiting quantum noise reduction in the proper spatial modes. Here we demonstrate a new technique that relies on a simple differential

beam displacement measurement and two mode quantum correlations in the form of a two-mode squeezed state to achieve beam deflection measurements with sensitivity below the SNL for typical AFM microcantilevers. A unique noise cancellation scheme allows for stable data acquisition over several hours without the use of stabilization of any sort aside from temperature controllers connected to the laser source. In particular, as a result of the position-noise cancellation brought on by the differential measurement, no stabilization of laser frequency or pointing stability is required, as might be expected for ultraprecise displacement measurements. This results in a remarkably accessible quantum sensing paradigm compared to typical sensors that make use of squeezed light.

For a typical optical power of $130 \mu\text{W}$, the microcantilever used was shot noise limited at ambient temperature and pressure for oscillation frequencies above 400 kHz, with an SNL of $3.39 \text{ fm}/\sqrt{\text{Hz}}$ and an SQL of $101 \text{ am}/\sqrt{\text{Hz}}$. The SNL exceeded the backaction noise for optical power less than 5 mW. Note that above 5 mW, squeezed states could still be used to reduce the total noise level, but backaction noise would determine the noise floor. Of course, existing back-action evasion techniques could be used in conjunction with our approach in order to simultaneously reduce the SQL and SNL. Likewise, for measurements performed at low temperature and pressure where thermal noise is dramatically reduced even at low frequencies, our approach can still be applied with low frequency squeezed states[17, 18] to further reduce the noise floor. Our detection technique relies on non degenerate four wave mixing (4WM) to produce twin beams with entangled spatial modes (sub-beam-size features) which exhibit quantum-correlated noise. When incident on a spatially resolving detector such as a conventional split photodiode, the correlated noise subtracts to yield a noise floor below the SNL for a differential measurement (see Fig. 1). The detector is simpler to align compared to interferometric techniques such as homodyne detection[8, 19], but yields the same noise floor when $\text{TEM}_{0,0}$ modes are used, owing to the fact that the squeezing measured by differential direct intensity beam displacement measurement is the same as a dual or multiplexed homodyne detector locked to the amplitude quadrature as shown in Fig. 1 (also see supplemental online material). On the other hand, we do not have access to the local oscillator phase, nor do we use a $\text{TEM}_{0,1}$ local oscillator and probe, and thus do not measure the beam's tilt in this configuration. However, the differential deflection technique is certainly compatible with homodyne detection as drop in replacement for split detectors. In comparison to weak measurement techniques[20, 21], our approach is deterministic and does not require post-processing.

It has been shown that 4WM in Rb vapor can produce quantum noise reduction spanning multiple spatial modes[5, 22, 23]. The system has also lent itself well to

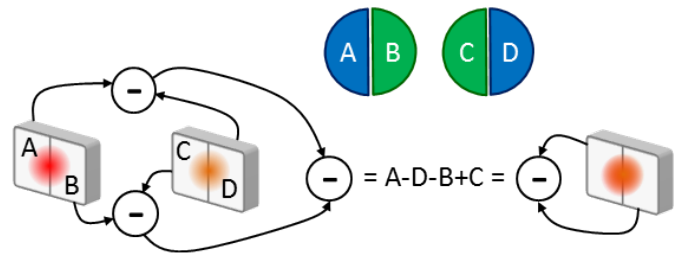


FIG. 1. Differential beam position measurements that make use of multiple spatial modes and twin beams. Due to conservation of momentum, the noise distribution of the conjugate beam is a reflection of the probe noise distribution about the center of the pump beam. The shaded semicircles represent the measured sections of each beam that contain whole or partial correlated coherence areas, which means that the position of each beam is also correlated. One may access these quantum correlations by performing a position difference measurement as shown on the left two split detectors (analogous to the intensity difference measurement that uncovers photon number correlations). One can exploit intensity difference measurements to effectively perform a position difference measurement: $P_- = A - B - (D - C)$. The two detectors need not be in the same location. Notably, it is also possible to perform the same differential beam displacement measurement with the twin beams combined on a single split diode, essentially acting as a multiplexed position detector. This ensures good common mode rejection and equivalent gain for each mode. Note that the twin beam beatnote (6 GHz) is well outside of the detector bandwidth of 5 MHz.

integration with several sensing scenarios, including surface plasmon resonance sensors, quantum-enhanced image sorting, compressive quantum imaging, and nonlinear interferometry[22, 24–26]. The ease of alignment afforded by the phase-insensitive amplifier configuration makes the generation of multi-spatial-mode quantum noise reduction accessible compared to implementations that use squeezed light in other sensors[8, 9, 19].

A schematic of the experimental configuration is shown in Fig. 2. A strong pump (150 mW) and weak probe (10 to $100 \mu\text{W}$) mix at a slight angle (0.3°) in a 12.7 mm long ^{85}Rb vapor cell held at 130°C . The pump and probe are both focused into the center of the cell with $800 \mu\text{m}$ and $400 \mu\text{m}$ waists respectively. The pump is detuned approximately 800 MHz to the red of the D1 line (795 nm), and the probe field is in turn detuned 3045 MHz to the blue from the pump. Figure 2(a) shows the energy level diagram, ground state hyperfine splitting, and virtual level which form a double lambda system.

During the 4WM process, two pump photons are absorbed simultaneously, resulting in coherence between the ground state levels. For every probe photon emitted, a corresponding conjugate photon with opposite detuning is emitted, satisfying energy conservation. Likewise, the angle of emission is opposite that of the probe in order to conserve momentum. As a result, the probe and

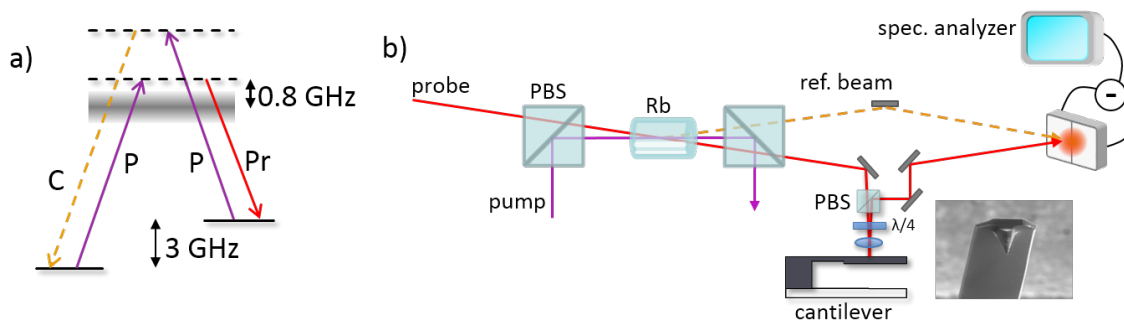


FIG. 2. a) The energy level diagram showing the double Λ system at the D1 line (795 nm) in ^{85}Rb . The probe (Pr) is detuned by approximately the ground state hyperfine splitting from the pump (P) field, which is off resonance by nearly 1 GHz. The dark state and attendant ground state coherence result in emission of a conjugate (C) photon for every emitted probe photon, satisfying energy and momentum conservation. The presence of a weak probe stimulates emission, while high nonlinear gain on the order of 5 allows for bright fields for both probe and conjugate. The blurred line representing the excited state represents the small hyperfine splitting between the excited levels compared to the ground state. b) Differential beam displacement measurement using split detectors. The probe is sent to a polarizing beam splitter (PBS) where it passes through a quarter wave retarder before being focused onto the cantilever by a microscope objective. On the return pass the probe beam is separated at the PBS and sent to a split detector (or through an aperture), which subtracts the correlated noise between each half of each beam.

conjugate fields in identical spatial modes have correlated intensities. These correlations manifest themselves as a lower noise floor in a measurement of the intensity difference between the beams (normalized to the SNL):

$$\langle \Delta(N_-)^2 \rangle = \frac{1}{\eta(2G - 1)}, \quad (2)$$

where N_- is the photon number difference operator, η is the combined transmission and detector efficiency, and G is the nonlinear intensity gain of the 4WM process.

In addition, macropixels of each beam known as coherence areas[27] are correlated pairwise across the beams, as shown in Fig. 1. In the limit that each coherence area could be described by a single spatial mode, and if each pair were isolated and the intensity difference measured, the quantum noise reduction would approach that of Eq. 2. A spatially resolving detector, such as a split photodiode, essentially performs this measurement when properly aligned. It has previously been shown that the spatial correlations in this system can be sampled in an arbitrary dimension[22] (also see online material). This allows for multiplexing a measurement of the correlations across two or more axes relative to the beam centers, which indicates that the twin beam correlations are well-suited to split measurements. Thus, while neither beam contains the perfect split noise mode ideal for beam displacement[9, 28], the beams contain sufficient spatial information to show reduced uncertainty in the relative displacement measurement. We illustrate this fact by showing that a sub-SNL displacement is detectable when one of the beams is reflected from a microcantilever with a characteristic shot noise level larger than its backaction noise.

To demonstrate sub-SNL displacement measurements,

two detector configurations were used to detect a position modulation generated by driving a microcantilever with a piezo-controlled tapping mode AFM mount at 745 kHz. First, razor blades were used as apertures in the beam paths in order to simulate a split detector and to aid in aligning the multi-spatial-mode contribution to the displacement measurement. As illustrated in Fig. 3(a), this configuration allowed for the direct measurement of microcantilever beam displacement with sensitivity beyond the shot noise level. When a razor blade was used to attenuate 50% of the probe beam, corresponding to the highest SNR for classical light, and a second razor blade was rastered across the conjugate, it was evident that maximum signal to noise ratio was coincident with maximum squeezing. This provides clear evidence that squeezed states always exceed the sensitivity of coherent states for MEMs beam deflection measurements, even when 50% attenuation is artificially introduced. On the other hand, when the spatial mode distribution of the probe was changed in its image plane relative to the conjugate by introducing spherical aberrations at the cantilever microscope objective, there was no enhancement in SNR over the classical case. When the spatial modes are misaligned, the subtraction of two states with thermal noise reduces to shot noise as long as the common mode rejection ratio (CMRR) of the detector exceeds the thermal noise. This method also serves as an immediate check of the system noise properties. The razor blades aid in alignment on a position sensitive detector by ensuring the probe and conjugate image planes are coincident on the detector and that no spherical aberrations are present. While this method proves that sub-SNL displacement measurements are possible, the gains are small due to absorption of 50% of the probe by the

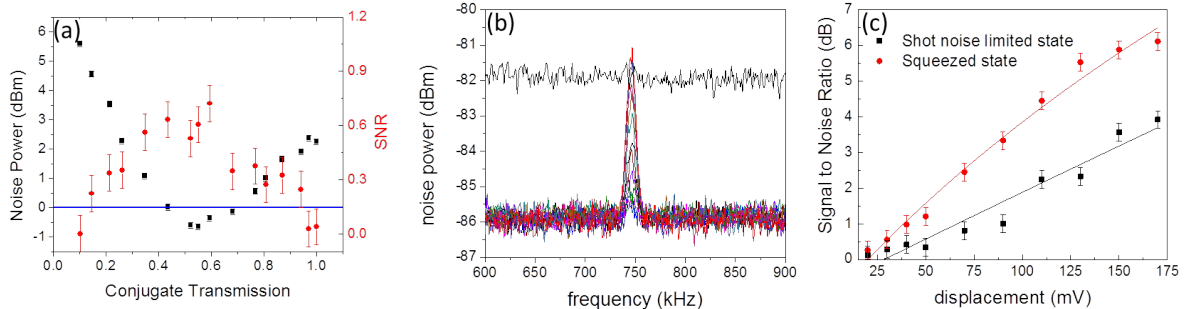


FIG. 3. (a) Sub shot noise modulation for a microcantilever with an aperture in the beam path, SNL-normalized noise-power and SNR as a function of conjugate transmission through an aperture with a constant probe transmission of 50%, (b) spectrum analyzer traces of raw displacement signals centered at 745 kHz for various displacement amplitudes, from 25 mV to 120 mV. The noise floor shows a broadband squeezing level of 4 dB relative to the shot noise level (black line, electronics noise subtracted). The spectrum analyzer settings were: resolution bandwidth: 10 kHz; video bandwidth: 100 Hz; sweep time: 2 s; 20 averages, and (c) Signal to noise ratio on a split detector vs increasing displacement modulation amplitude at 745 kHz for a squeezing level of 3 dB. The squeezed SNR increases more rapidly than the coherent case to a separation of 3 dB in the limit of large displacement.

razor blade, and further, while apertured detectors are commonly used in displacement measurements, the artificial introduction of loss means that they can not provide maximum signal to noise. Indeed, the minimum detectable displacement also depends on the losses[4]. The SNR and measured noise level outlined in Fig. 3(a) correspond to a maximum increase in SNR of 0.7 ± 0.1 dB vs the classical case. This enhancement can be improved dramatically by utilizing high quantum efficiency quadrant detectors in place of the apertured photodiodes.

The balanced split detectors illustrated in Fig. 1 yield the optimal SNR associated with traditional split detector schemes[4], the stability associated with traditional balanced detection schemes, and function similarly to homodyne detectors with a position-modulated local oscillator. The individual diodes in each split detector have 96% quantum efficiency, and utilizing a single split diode to measure relative probe and conjugate beam position ensures that the diodes are “matched” (having quantum efficiency and terminal capacitance as close as possible to one another). When using separate split diodes for each beam, the electronic gain and frequency response of each can be tuned to account for any mismatch with the added advantage that the probe and conjugate fields can be spacelike separated by a large distance.

The data presented in Fig. 3(b) and (c) were acquired with probe and conjugate combined on a single split detector, and the microcantilever was again modulated at 745 kHz with an amplitude of 20-170 mV. Figure 3(b) shows data for amplitudes of 25-120 mV with a noise floor 4.0 ± 0.1 dB lower than would be possible with classical readout light at the same optical power. In the limit of large displacements, the SNR is determined by the amount of quantum noise reduction available in the readout light, meaning that an increase in SNR by 4 dB is

directly observable. For the 10kHz resolution bandwidth used for these measurements, this results in a reduction of the minimum resolvable cantilever displacement from 339 ± 1.2 fm to 135 ± 1.2 fm - enabling the measurement of displacements previously obscured by shot noise. By applying a state of the art squeezed state with 10 dB, it would be possible to reduce the minimum resolvable displacement by an order of magnitude. In Fig. 3(c), the measured signal to noise ratio is plotted as a function of microcantilever modulation, illustrating the same effect for a squeezing level of 2.8 ± 0.1 dB. To the extent that squeezing exceeds the single-beam SNL for an equivalent power, as we have demonstrated here, the readout strategy that uses squeezed light will always yield better results than any readout strategy using coherent light alone.

It is notable that some drift in the DC displacement of both the probe and conjugate beams is present due to air currents within the Rb cell. However, due to momentum conservation, the probe drift is canceled by an equivalent drift in the conjugate beam. Any residual differential drift is negligible at the 745 kHz displacement frequency under study. The pointing correlations are reliable enough to ensure a stable measurement over the course of several hours with no stabilization of any sort in the experiment.

To conclude, the use of multi-spatial-mode squeezed states provides the first direct measurement of microcantilever beam deflection below the SNL. The results are applicable to any cantilever device operating with minimal back action noise, including nano-electro-mechanical-systems (NEMS), which have recently been shown to be shot-noise-limited[29] at frequencies of a few MHz. The 4WM process has approximately 50 MHz of bandwidth within which to demonstrate sub-SNL dis-

placement for NEMs and MEMs structures. The experimental configuration is simple compared to most quantum sensing applications which require multiple optical cavities, cavity length locks, and phase locks. Here, no stabilization is required; instead the twin beam correlations cancel any excess position-noise. Further, interference measurements, while possible in this configuration, are not necessary to achieve high SNR displacements. In addition, the 4WM process supports arbitrary probe spatial profiles, allowing for additional improvement in sensitivity via the choice of appropriate spatial structures by placing a spatial light modulator before the vapor cell[22].

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The authors declare that they have no competing financial interests.

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- [1] Rugar, D., Budakian, R., Mamin, H. & Chui, B. Single spin detection by magnetic resonance force microscopy. *Nature* **430**, 329–332 (2004).
- [2] Arlett, J., Myers, E. & Roukes, M. Comparative advantages of mechanical biosensors. *Nature nanotechnology* **6**, 203–215 (2011).
- [3] LeMieux, M. C. *et al.* Polymeric nanolayers as actuators for ultrasensitive thermal bimorphs. *Nano letters* **6**, 730–734 (2006).
- [4] Fukuma, T., Kimura, M., Kobayashi, K., Matsushige, K. & Yamada, H. Development of low noise cantilever deflection sensor for multienvironment frequency-modulation atomic force microscopy. *Review of Scientific Instruments* **76**, 053704–053704 (2005).
- [5] Boyer, V., Marino, A. M., Pooser, R. C. & Lett, P. D. Entangled images from four-wave mixing. *Science* **321**, 544–547 (2008).
- [6] Vahlbruch, H. *et al.* Observation of squeezed light with 10-db quantum-noise reduction. *Physical review letters* **100**, 033602 (2008).
- [7] Schnabel, R., Mavalvala, N., McClelland, D. E. & Lam, P. K. Quantum metrology for gravitational wave astronomy. *Nature communications* **1**, 121 (2010).
- [8] Taylor, M. A. *et al.* Biological measurement beyond the quantum limit. *Nature Photonics* **7**, 229–233 (2013).
- [9] Treps, N. *et al.* A quantum laser pointer. *Science* **301**, 940–943 (2003).
- [10] Smith, D. Limits of force microscopy. *Review of scientific instruments* **66**, 3191–3195 (1995).
- [11] Putman, C. A., De Groot, B. G., Van Hulst, N. F. & Greve, J. A detailed analysis of the optical beam deflection technique for use in atomic force microscopy. *Journal of Applied Physics* **72**, 6–12 (1992).
- [12] Picco, L. *et al.* Breaking the speed limit with atomic force microscopy. *Nanotechnology* **18**, 044030 (2007).
- [13] Verlot, P., Tavernarakis, A., Briant, T., Cohadon, P.-F. & Heidmann, A. Backaction amplification and quantum limits in optomechanical measurements. *Physical review letters* **104**, 133602 (2010).
- [14] Arcizet, O., Cohadon, P.-F., Briant, T., Pinard, M. & Heidmann, A. Radiation-pressure cooling and optomechanical instability of a micromirror. *Nature* **444**, 71–74 (2006).
- [15] Teufel, J., Donner, T., Castellanos-Beltran, M., Harlow, J. & Lehnert, K. Nanomechanical motion measured with an imprecision below that at the standard quantum limit. *Nature nanotechnology* **4**, 820–823 (2009).
- [16] Anetsberger, G. *et al.* Measuring nanomechanical motion with an imprecision below the standard quantum limit. *Physical Review A* **82**, 061804 (2010).
- [17] McCormick, C. F., Marino, A. M., Boyer, V. & Lett, P. D. Strong low-frequency quantum correlations from a four-wave-mixing amplifier. *Phys. Rev. A* **78**, 043816 (2008).
- [18] Liu, C. *et al.* Realization of low frequency and controllable bandwidth squeezing based on a four-wave-mixing amplifier in rubidium vapor. *Optics letters* **36**, 2979–2981 (2011).
- [19] Hoff, U. B. *et al.* Quantum-enhanced micromechanical displacement sensitivity. *Optics letters* **38**, 1413–1415 (2013).
- [20] Hosten, O. & Kwiat, P. Observation of the spin hall effect of light via weak measurements. *Science* **319**, 787–790 (2008).
- [21] Dixon, P. B., Starling, D. J., Jordan, A. N. & Howell, J. C. Ultrasensitive beam deflection measurement via interferometric weak value amplification. *Physical review letters* **102**, 173601 (2009).
- [22] Lawrie, J. & Pooser, R. C. Toward real-time quantum imaging with a single pixel camera. *Optics Express* **21**, 7549–7559 (2013).
- [23] Qin, Z. *et al.* Compact diode-laser-pumped quantum light source based on four-wave mixing in hot rubidium vapor. *Optics Letters* **37**, 3141–3143 (2012).
- [24] Lawrie, B., Evans, P. & Pooser, R. Extraordinary optical transmission of multimode quantum correlations via localized surface plasmons. *Physical Review Letters* **110**, 156802 (2013).
- [25] Clark, J. B., Zhou, Z., Glorieux, Q., Marino, A. M. & Lett, P. D. Imaging using quantum noise properties of light. *arXiv preprint arXiv:1207.1713* (2012).
- [26] Jing, J., Liu, C., Zhou, Z., Ou, Z. & Zhang, W. Realization of a nonlinear interferometer with parametric amplifiers. *Applied Physics Letters* **99**, 011110–011110 (2011).
- [27] Jedrkiewicz, O. *et al.* Detection of sub-shot-noise spatial correlation in high-gain parametric down conversion. *Phys. Rev. Lett.* **93**, 243601 (2004).
- [28] Pinel, O. *et al.* Ultimate sensitivity of precision measurements with intense gaussian quantum light: A multimodal approach. *Physical Review A* **85**, 010101 (2012).
- [29] Hiebert, W., Vick, D., Sauer, V. & Freeman, M. Optical interferometric displacement calibration and

thermomechanical noise detection in bulk focused ion beam-fabricated nanoelectromechanical systems. *Jour-*

nal of Micromechanics and Microengineering **20**, 115038 (2010).